Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	"6051503".pn.	USPAT	OR	ON	2004/12/27 07:52
L2	35370	plasma and (etch or etching) and semiconductor	US-PGPUB; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:56
L3	119	2 and ((ramp or ramping) and (etch$1stop$3 or (etch adj stop$3)))	US-PGPUB; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:57
L4	0	jacobs-Keren.in.	US-PGPUB; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:57
L5	0	Jacobs-Keren.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:58
L6	5	Eppler-Aaron.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:58
L7	272	plasma and selectivity and (ramp or ramping) and pressure	US-PGPUB; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/27 07:59
S301	4966	damascene	USPAT	OR	ON	2004/11/12 14:09
S302	530	S301 and "CF.sub.4" and (oxygen or "O.sub.2")	USPAT	OR	ON	2004/11/12 14:10
S303	277	S301 and ("CF.sub.4" with (oxygen or "O.sub.2"))	USPAT	OR	ON	2004/11/12 14:11
S304	103	S303 and ((nitrogen or "N.sub.2") with (hydrogen or "H.sub.2"))	USPAT	OR	ON	2004/11/12 14:16
S305	86	S304 and @ay<="2001"	USPAT	OR	ON	2004/11/12 14:16
S306	326	plasma and selectivity and (ramp or ramping) and pressure	USPAT	OR	ON	2004/12/27 07:59
S307	297	S306 and @py<="2003"	USPAT	OR	ON	2004/11/22 15:15

S30 8	175	S307 and (controller or processor or computer)	USPAT	OR	ON	2004/11/22 15:17
S30 9	109	S308 and (etch or etching)	USPAT	OR	ON	2004/11/22 15:17
S31 0	621	(third near4 plasma) and (selectivity or selective)	USPAT	OR	ON	2004/11/22 16:00
S31 1	420	S310 and @ay<="2003" and semiconductor	USPAT	OR	ON	2004/11/22 16:00
S31 2	388	S311 and (etch or etching)	USPAT	OR	ON	2004/11/22 16:01
S31 3	86	S312 and (etch$1stop or (etch$3 adj stop) or (etch$3 adj stopping))	USPAT	OR	ON	2004/11/22 16:01
S31 4	84	S313 and @py<="2003"	USPAT	OR	ON	2004/11/22 17:29
S31 5	1	"6638781".pn.	USPAT	OR	ON	2004/11/22 17:30
S31 6	1	"6638871".pn.	USPAT	OR	ON	2004/11/22 17:37
S31 7	3	"4729815".pn. "5807789".pn. "5843226".pn.	USPAT	OR	ON	2004/11/22 17:37
S31 8	1	"6762132".pn.	USPAT	OR	ON	2004/11/29 13:32
S31 9	1	"6051503".pn.	USPAT	OR	ON	2004/11/29 14:57
S32 0	42678	plasma and (etch or etching) and semiconductor	USPAT	OR	ON	2004/12/27 07:56
S32 1	3	S320 and ((ramp or ramping) same (etch$1stop$3 or (etch adj stop$3)))	USPAT	OR	ON	2004/11/29 14:58
S32 2	170	S320 and ((ramp or ramping) and (etch$1stop$3 or (etch adj stop$3)))	USPAT	OR	ON	2004/12/27 07:57
S32 3	119	S322 and @py<="2002"	USPAT	OR	ON	2004/11/29 14:59
S32 4	5202	S320 and controller	USPAT	OR	ON	2004/11/29 15:37
S32 5	1227	S324 and outlet	USPAT	OR	ON	2004/11/29 15:37
S32 6	1130	S325 and chamber	USPAT	OR	ON	2004/11/29 15:38
S32 7	494	S326 and (computer or CPU)	USPAT	OR	ON	2004/11/29 15:38
S32 8	479	S327 and pressure	USPAT	OR	ON	2004/11/29 15:38

S329	479	S328 and chamber	USPAT	OR	ON	2004/11/29 15:39
S330	313	S329 and electrode	USPAT	OR	ON	2004/11/29 15:39
S331	222	S330 and @py<="2002"	USPAT	OR	ON	2004/11/29 16:07
S332	1	"6025255".pn.	USPAT	OR	ON	2004/11/29 16:39
S333	4	(ramp or ramping) same (etch$1stop$4 or (etch adj stop$4))	USPAT	OR	ON	2004/11/29 16:44
S334	712	rate with (etch$1stop$4 or (etch adj stop$4))	USPAT	OR	ON	2004/11/29 16:44
S335	0	S334 and semiconducotor and plasma	USPAT	OR	ON	2004/11/29 16:45
S336	488	S334 and semiconductor and plasma	USPAT	OR	ON	2004/11/29 16:45
S337	481	S336 and @ay<="2002"	USPAT	OR	ON	2004/11/29 16:45
S338	27	S337 and (ramp or ramping)	USPAT	OR	ON	2004/11/29 16:45